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Art Unit: Unassigned

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APR 20 (33)

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Title: METHOD FOR PRODUCING HIGH-SURFACE AREA TEXTURING OF A SUBSTRATE, SUBSTRATES PREPARED THEREBY AND

MASKS FOR USE THEREIN

Serial No.: 09/233,694

Filed: January 19, 1999

In the Application of Brennen et al.

U.S. PATENT DOCUMENTS

| Exam. Init. | Ref. Desig. | Document No. | Date | Name | Class | Sub Class | Filing Date |
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| Cuy | AA-1 | 4,478,677 | Oct. 23, 1984 | Chen et al. | | | |
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| Cuy | AH-1 | 7-241690 | 19 September 1995 | Japan | | | X abstract only |
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| Exam. Init. | Ref. Desig. | Description |
| ly | AJ-1 | Krajnovich et al., "Formation of 'Intrinsic' Surface Defects During 248 mn Photoablation of Polyimide," <i>J. Appl Phys.</i> <u>73</u> :3001-3008 (1993) |

Examiner:

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EXAMINER: Initial of citation considered whether or not the citation conforms with MPEP609. Draw a line through the citation if not in conformance and not considered. Include copy of this form with next communication to applicant.